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Contents

vii ix	Authors Conference Committee	
SESSION 1	DESIGN, DEVELOPMENT, AND FABRICATION OF PHOTONIC INSTRUMENTS I	
10925 02	Optimization for as-built performance (Invited Paper) [10925-1]	
10925 03	Structural, Thermal, and Optical Performance (STOP) analysis of the NASA ARCSTONE instruments [10925-2]	
10925 05	Lens design using grid-based surface optimization [10925-4]	
SESSION 2	APPLICATIONS OF PHOTONIC INSTRUMENTS	
10925 06	Sub-nanosecond time-gated camera based on a novel current-assisted CMOS image sensor (Invited Paper) [10925-5]	
10925 07	Focus adjustable motion-blur compensation method using deformable mirror [10925-6]	
10925 08	Active fiber ring enhanced absorption gas spectroscopy using multi-longitudinal mode tunable laser in the NIR [10925-7]	
10925 09	Photothermal microscopy characterization of multiphoton annealing of defects in thin-film coatings for high-power lasers [10925-9]	
10925 0A	Label-free 3D super-resolution nanoscope with large field-of-view [10925-10]	
10925 OB	Multispectral imaging system for the structural analysis of highly transparent technical surfaces [10925-11]	
SESSION 3	METROLOGICAL INSTRUMENTATION I	
10925 0D	Characterization of gradient index optical components using experimental ray tracing [10925-13]	
10925 OE	In-process monitoring of laser ablation on thin steel membranes by multispectral shape-from-shading [10925-14]	

10925 OF	Specifying polarimetric tolerances of a high-resolution imaging multiple-species atmosphere profiler (HiMAP) [10925-15]
SESSION 4	METROLOGICAL INSTRUMENTATION II
10925 01	High-resolution wave front phase sensor for silicon wafer metrology [10925-18]
10925 OK	Absolute calibration of a Shack-Hartmann wavefront sensor for measurements of wavefronts [10925-20]
SESSION 5	METROLOGY, CHARACTERIZATION, AND FABRICATION OF PHOTONIC INSTRUMENTS I
10925 OL	Thin-film characterization with a dual-channel dispersion-encoded imaging low-coherence interferometry approach [10925-21]
10925 00	Chromatic line confocal technology in high-speed 3D surface-imaging applications [10925-24
10925 OP	An economical solution for high-throughput low-noise multi-channel spectroscopy [10925-25]
SESSION 6	METROLOGY, CHARACTERIZATION, AND FABRICATION OF PHOTONIC INSTRUMENTS II
10925 OS	Influence of numerical aperture (NA) on micro-reflectance spectroscopy [10925-28]
SESSION 7	DESIGN, DEVELOPMENT, AND FABRICATION OF PHOTONIC INSTRUMENTS II
10925 OU	True OEM terahertz systems for industrial applications (Invited Paper) [10925-30]
10925 0V	Multi-tone modulated continuous-wave lidar [10925-31]
10925 OW	Performance analysis of linearly swept frequency modulated continuous-wave ladar (Invited Paper) [10925-32]
10925 OX	Wavelength-locking of a semiconductor laser using an electronic technique [10925-33]
10925 0X SESSION 8	Wavelength-locking of a semiconductor laser using an electronic technique [10925-33] SENSORS AND RUGGEDIZED SYSTEMS

10925 10	A compact DUV spectrometer for wide-temperature entry, descent, and landing sensing applications [10925-36]
10925 11	Simulation study of optical detection of small particles by light scattering-type sensor with double-side mirror reflectors [10925-37]
10925 12	Vector Brillouin optical time-domain analysis with Raman amplification and optical pulse coding [10925-38]
SESSION 9	DESIGN, DEVELOPMENT, AND FABRICATION OF PHOTONIC INSTRUMENTS III
10925 13	Lens in a voice coil: a compact design approach for z-scanners (Invited Paper) [10925-39]
10925 14	A frequency modulated laser interferometer for nanometer-scale position sensing at cryogenic temperatures [10925-40]
	POSTER SESSION
10925 16	Electro-optic-based pressure measurement and transmitter using lithium niobate (LiNbO ₃) Mach-Zehnder modulator for industrial application [10925-42]
10925 17	Polarized wavefront measurement using an electrically tunable focused plenoptic camera [10925-44]
10925 18	New microcontroller unit improving stability and functionality of the optical chopper for atmospheric LIDAR $[10925-45]$
10925 19	Development of separation inspection technique for micro-cracks and particles using non-contact stress-induced light scattering method [10925-46]
10925 1A	Combination of lock-in detection with dual-comb spectroscopy [10925-47]
10925 1B	Microspectroscopy of nanomaterials, biological species, and live cells [10925-49]
10925 1C	Characterization of performance of back-illuminated sCMOS cameras for microscopy applications versus conventional sCMOS and EMCCD cameras [10925-50]